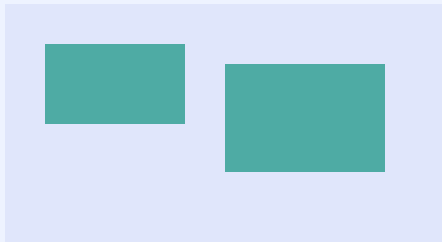
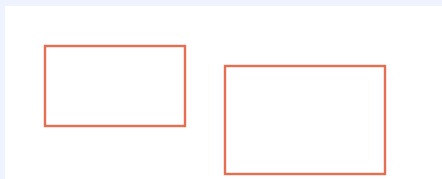


Electron Microscopy Modalities and Parameters (Conceptual)

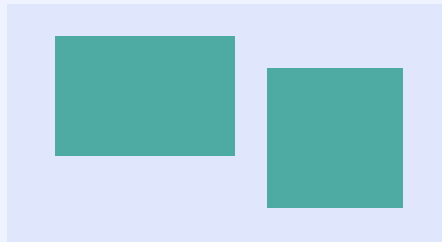
TEM ($T_{\text{low}}=30$, $T_{\text{high}}=100$, $A_{\text{min}}=100$)



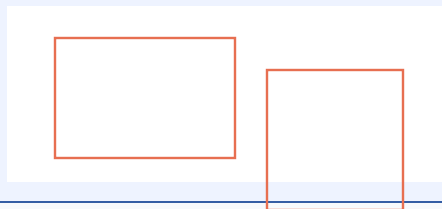
Edge detection



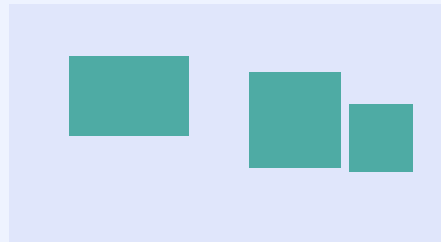
SEM ($T_{\text{low}}=50$, $T_{\text{high}}=150$, $A_{\text{min}}=500$)



Edge detection



Cryo-EM ($T_{\text{low}}=20$, $T_{\text{high}}=80$, $A_{\text{min}}=50$)



Edge detection

